

Supporting Information

High Performance MoO_{3-x}/Si Heterojunction Photodetectors with Nanoporous Pyramid Si Arrays for Visible Light Communication

Application

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1. Calculation method

Calculations of the depletion layer thickness (W) and the hole drift time (τ_p) in depletion layer.

The depletion layer thickness (W) can be calculated by:

$$W = \sqrt{\frac{2\epsilon_s V_{bi}}{qN_D}} \quad (1)$$

ϵ_s is dielectric constant of silicon (11.9^[1]), V_{bi} is the build-in potential (~670 mV), q is the unit electron charge and N_D is the doping concentration ($2 \times 10^{15} \text{ cm}^{-3}$). The depletion layer thickness was calculated as 223 nm.

The hole drift velocity is defined by:

$$V_p = \mu_p E \quad (2)$$

The μ_p is the hole mobility in silicon ($450 \text{ cm}^2\text{V}^{-1}\text{s}^{-1}$ in silicon with doping concentration of $2 \times 10^{15} \text{ cm}^{-3}$) and E is built-in electric field and can be calculated by:

$$E = \frac{V_{bi}}{W} \quad (3)$$

According equation (1) (2) (3), the hole drift velocity (V_p) was calculated to be $1.5 \times 10^5 \text{ m s}^{-1}$.

Therefore, the hole drift time (τ_p) was calculated by:

$$\tau_p = \frac{W}{V_p} \quad (4)$$

And the hole drifting time (τ_p) was estimated to be 2.23 ps.

Estimation of rise time (τ_r)

The diffusion length (L) of minority carrier and minority carrier lifetime (τ) is associated with the following formula:

$$L = (D \cdot \tau)^{1/2} \quad (5)$$

D is diffusion coefficient, and it is defined by:

$$D = \mu_p \cdot \frac{kT}{q} \quad (6)$$

The μ_p is the hole mobility in silicon. k is Boltzmann constant. T is *Kelvin* temperature (300 K at room temperature). q is the unit electron charge.

According to (5) and (6), the minority carrier diffusion velocity (V) is calculated by

$$V = \frac{L}{\tau} = \frac{\sqrt{D\tau}}{\tau} \quad (7)$$

The lifetime (τ) can be found in the related article [2]. The lifetime in n-type silicon (doping concentration of $2 \times 10^{15} \text{ cm}^{-3}$) is about 20 μs .

Therefore, the rise time τ_r was calculated by the equation:

$$\tau_r = \frac{l}{V} \quad (8)$$

l is the thickness of silicon wafer (450 μm). According to above formula, the rise time was estimated to be 73 μs .

2. Table S1

The overall photodetecting performance of three devices.

<i>Heterojunction structure</i>	<i>R (mA/W)</i>	<i>τ_r (μs)</i>	<i>τ_d (μs)</i>	<i>f_{-3dB} (Hz)</i>	<i>D^* (jones)</i>	<i>SNR</i>
<i>Planar</i>	54	5.4	130	2.1×10^3	4.99×10^{12}	2.5×10^4
<i>Pyramid</i>	79	1.89	58	1.0×10^4	7.3×10^{12}	8.5×10^4
<i>NPPAs</i>	138	0.87	23	5.0×10^4	1.27×10^{13}	1.51×10^5

3. Figures

Figure S1

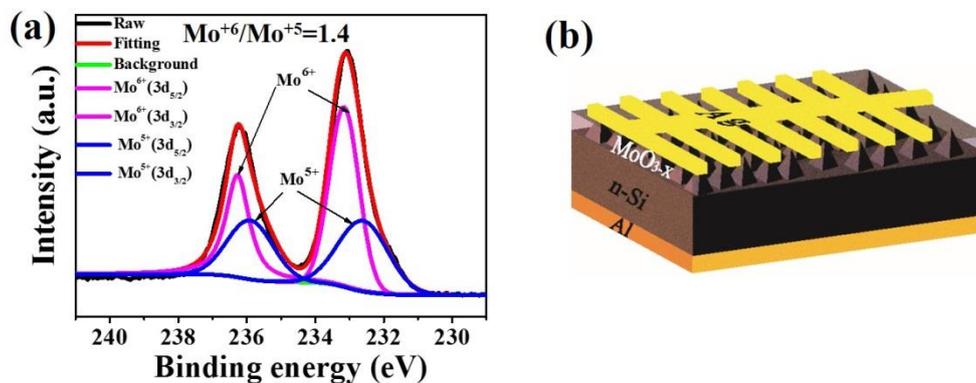


Figure S1. (a). XPS spectrum of as-deposited MoO_{3-x} thin films. (b). Schematic diagram of the MoO_{3-x}/n-Si heterojunction photodetector with pyramid structure.

Figure S2

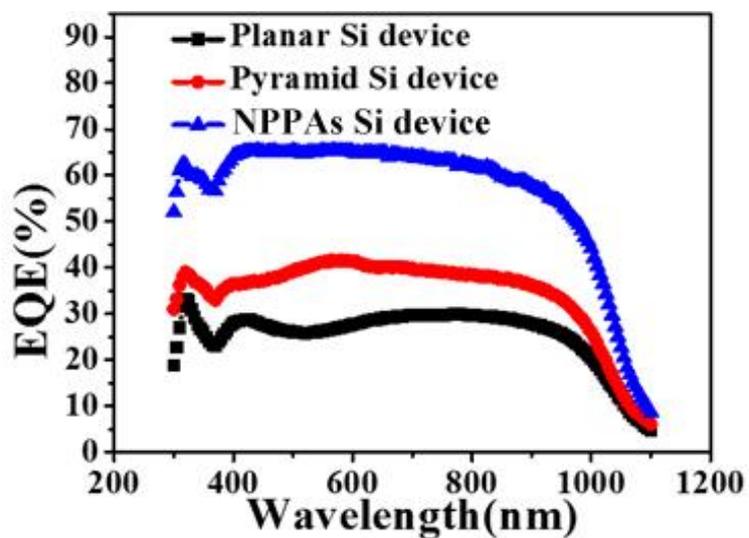


Figure S2. External quantum efficiency (EQE) of three devices ranges.

Figure S3

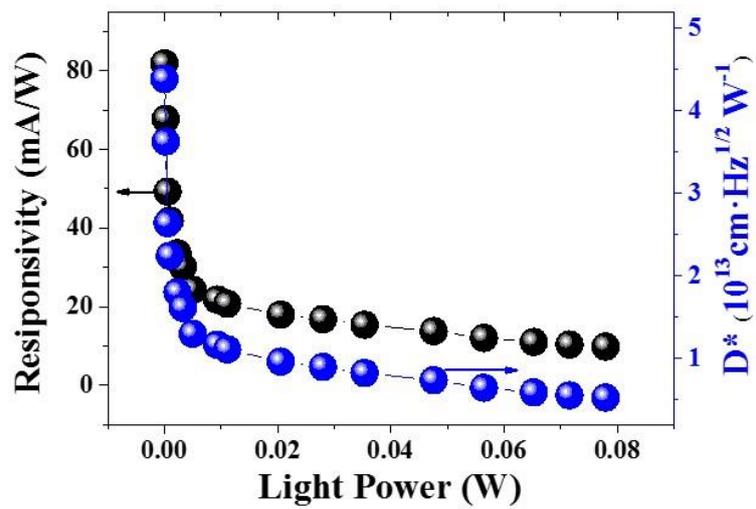


Figure S3. The detectivity (D^*) and responsivity (R) of NPPAs device under different power density of 650 nm laser.

Figure S4

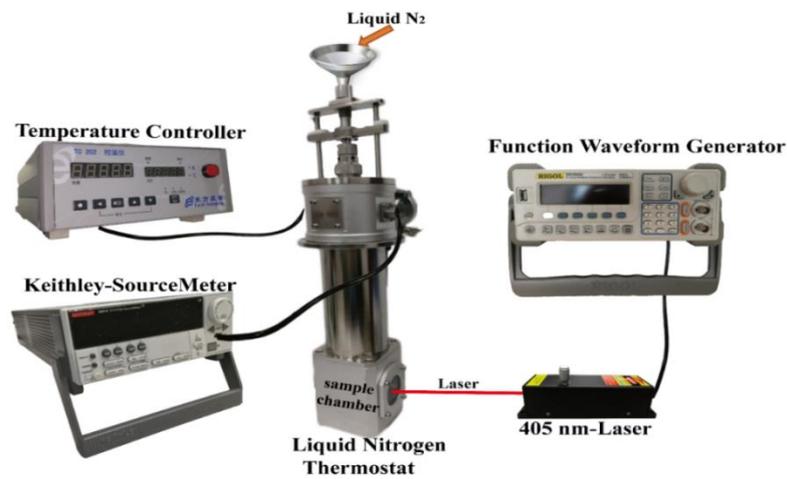


Figure S4. The setups for temperature cycling measurements.

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2. Panek, P., The Influence of the Base Material Parameters on Quantum and Photoconversion Efficiency of the Si Solar Cells. *Archives of Metallurgy and Materials* **2016**, 61 (4).